



# On-Line Testing of Ohmic RF MEMS Switches for SiP Applications

Jari Hannu, Markus Ängeslevä and Markku Moilanen

Optoelectronics and Measurement Techniques Laboratory  
University of Oulu, Finland

## Outline

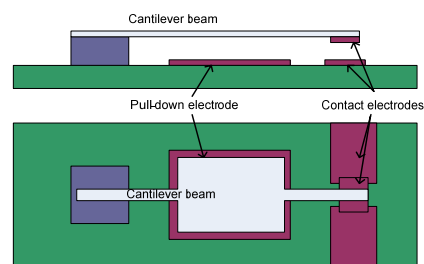
- ▶ Introduction
- ▶ Lifetime of an ohmic RF MEMS switch
- ▶ Analog boundary scan on SiP level
- ▶ On-line test method for ohmic RF MEMS switch
- ▶ Measurements and results
- ▶ Future directions
- ▶ Conclusions

## Introduction

- ▶ RF MEMS switches are promising when compared to existing RF switches
  - Near-zero power consumption
  - Very high isolation
  - Very low insertion loss
- ▶ But there is also some disadvantages
  - Low speed
  - Power handling
  - Packaging
  - **Reliability**

## RF MEMS switches

- ▶ RF MEMS switches can roughly be categorized by the switching method to capacitive and ohmic switches



- ▶ Ohmic switches are typically electrostatically actuated
  - Pull-down electrode pulls the cantilever down to enable contact between electrodes

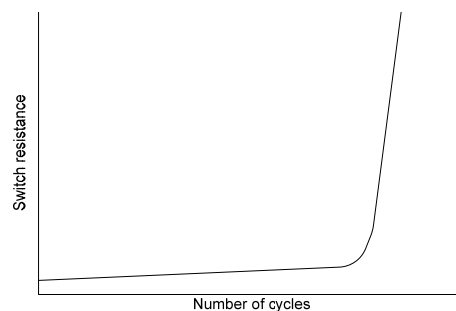
## Life-time of an ohmic RF MEMS switch

- ▶ RF-power loss consists of three components: return loss, isolation loss and ohmic resistance
- ▶ Ohmic resistance consists of package wiring and switch resistance
  - Typically the nominal switch resistance is  $\leq 1\ \Omega$
- ▶ The power loss is usually dominated by the switch resistance

$$Loss = 10 \log_{10} \left( \frac{Z_0}{Z_0 + R_{sw}} \right)$$

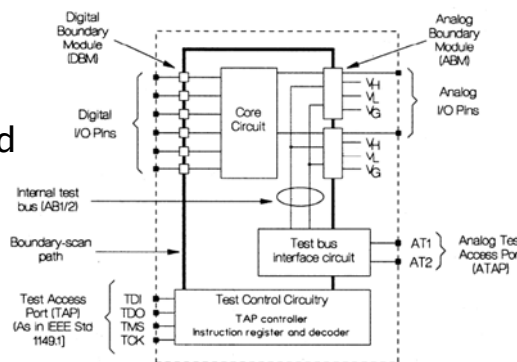
## Life-time of an ohmic RF MEMS switch

- ▶ The switch resistance increases as a function of switching cycles
  - Caused of the switch contact degradation
- ▶ The speed of resistance increase depends of the switching type
  - Cold switching can be tolerated several decades cycles more than hot switching



## Analog boundary scan on SiP level

- ▶ IEEE Std 1149.4 “Standard for a Mixed-Signal Test Bus”
  - Bases on IEEE Std 1149.1
  - Defines testability structures for mixed-signal circuits
  - Standard will be updated in 2008
- ▶ Powerful test method but has not gained such popularity as 1149.1



## Analog boundary scan on SiP level

- ▶ 1149.4 can be used as test access for SiP devices from production to field tests
- ▶ Implementing 1149 to SiP is a challenge due SiP adds a hierarchy layer to a board design
  - SiP is seen as a single IC on board while it can have multiple IC's inside
  - Solution is presented for 1149.1\*
- ▶ Extending the solution to 1149.4 only requires routing the analog test lines to required IC

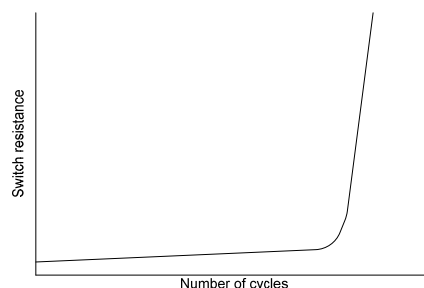
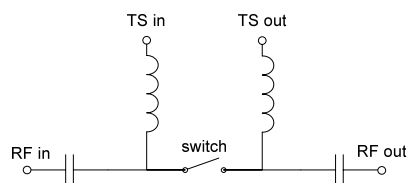
\*F. de Jong, A. Biewenga, “SiP-TAP: JTAG for SiP”, International Test Conference 2006

## Analog boundary scan on SiP level

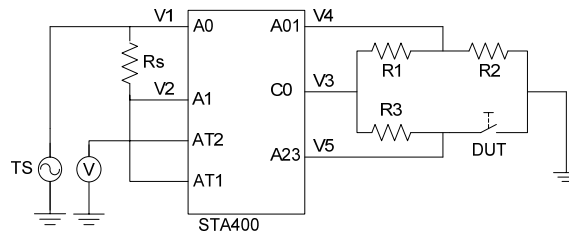
- ▶ 1149.4 creates an generic analog access which can be used for
  - Component testing
  - Health monitoring
  - Signal routing
  - etc
- ▶ Test access is reusable from manufacturing level to on-line field tests
  - Critical component monitoring
  - Power on self-test, etc
  - Requires test signal measurement and generation

## On-line test method for ohmic RF MEMS switch

- ▶ Test method is based on simple resistance measurements of the ohmic RF MEMS switch while it is on switch-on mode
- ▶ The resistance change reveals the aging of the component

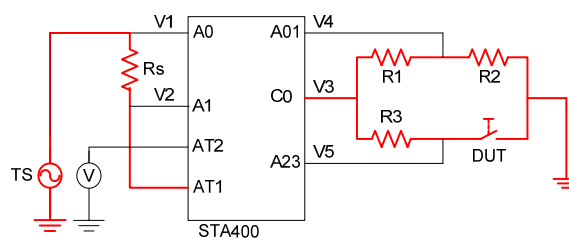


## On-line test method for ohmic RF MEMS switch



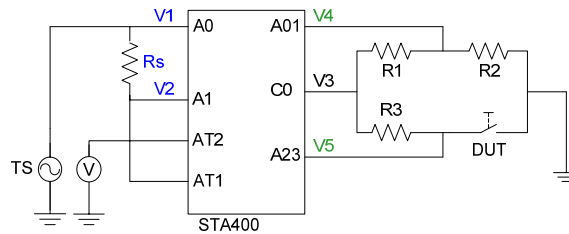
- ▶ 1149.4 environment was used for on-resistance measurements
- ▶ The small resistance measurement is based on Wheatstone bridge circuit
  - Successfully used in BGA junction monitoring

## On-line test method for ohmic RF MEMS switch



- ▶ Resistances  $R_s$  and  $R_1$ – $R_3$  are known
- ▶ The test signal routed thru  $R_s$  to pin AT1
- ▶ From AT1 the test signal is routed internally through C0 to the bridge circuit
- ▶ The pin voltages are measured internally through AT2

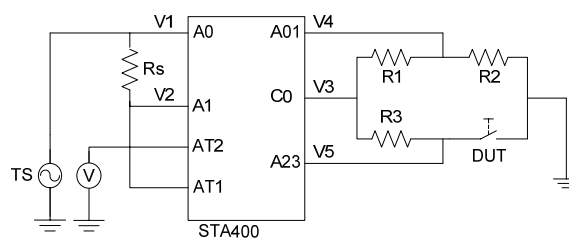
## On-line test method for ohmic RF MEMS switch



- ▶ The test signal current  $I$  can be calculated from voltages in points  $V_1$  and  $V_2$  and from the resistance  $R_s$
- ▶ The off balance voltage  $V_G$  can be calculated from the measured voltages  $V_4$  and  $V_5$

$$I = \frac{V_1 - V_2}{R_s} \quad V_G = V_4 - V_5$$

## On-line test method for ohmic RF MEMS switch

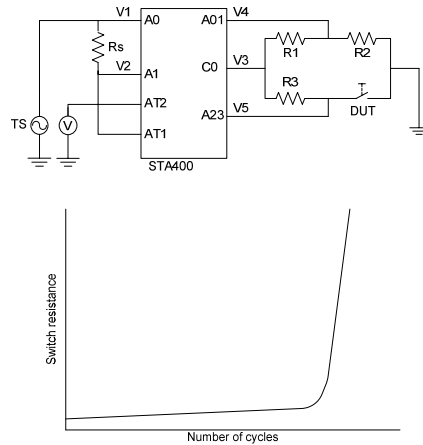


- ▶ Using calculated values  $V_G$  and  $I$  and previously known resistances  $R_1$ – $R_3$  we can calculate the switch on resistance  $R_{SW}$

$$R_{SW} = \frac{R_2 R_3}{R_1 - \frac{V_G}{I}} + \frac{V_G}{I} \frac{R_1 + R_2 + R_3}{R_1 - \frac{V_G}{I}}$$

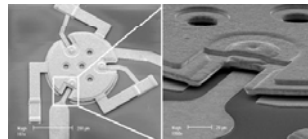
## On-line test method for ohmic RF MEMS switch

- ▶  $R_{SW}$  can be used to estimate the current condition of the switch
- ▶ Significant increase  $R_{SW}$  or crossing predefined boundary value indicates the end of switch life



## Measurements and results

- ▶ Device Under Test
  - Commercial ohmic RF MEMS Single Pole Double-Throw switch (Teravicta)
  - Bandwidth DC to 7 GHz
  - Initial switch on-resistance  $0.3 \Omega$
  - Requires 68 V actuating signal



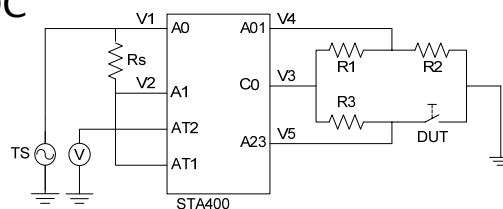
## Measurements and results

- ▶ Measurement environment
  - Switch cycling was done with charge pump driven by a signal generator (HP 33120A)
  - Cycling monitored with a universal counter (HP 5316A)
  - Test signal for 1149.4 measurement by signal generator
  - 1149.4 environment controlled by BS controller (JTAG PM4705)
  - Overall measurement controlled by LabVIEW



## Measurements and results

- ▶ The used switch actuation frequency 1 kHz
- ▶ Cold switching
- ▶ Test signal 1 mA DC
- ▶ Component values
  - $R_S = 1 \text{ k}\Omega$
  - $R_1 = R_2 = 10 \text{ k}\Omega$
  - $R_3 = 0.3 \text{ }\Omega$

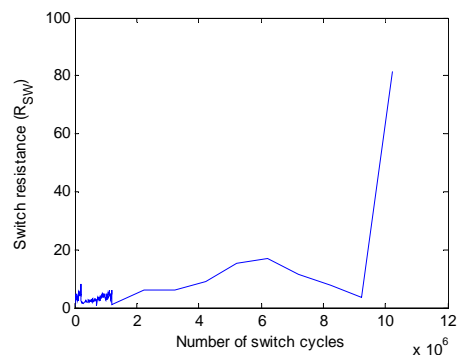


## Measurements and results

- ▶ Before testing actual switches, measurement environment was validated with resistors
- ▶ Two MEMS switches were tested
  - 1<sup>st</sup> component was broken before measurements
  - 2<sup>nd</sup> component was broken without any early warning signs

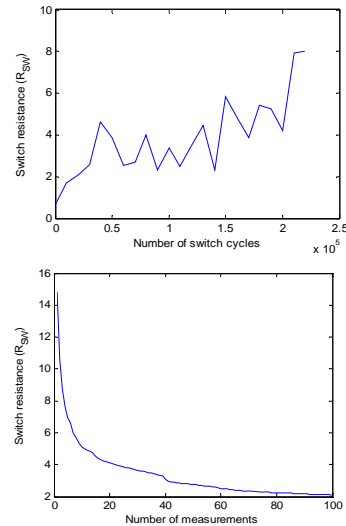
## Measurements and results

- ▶ 1<sup>st</sup> ohmic RF MEMS switch
  - Was initially broken
  - Measurements done in three phases
    1. 220 000 cycles  
measured after 10 000
    2. 1 000 000 cycles,  
measured after 10 000
    3. 11 000 000 cycles,  
measured after 1 000 000



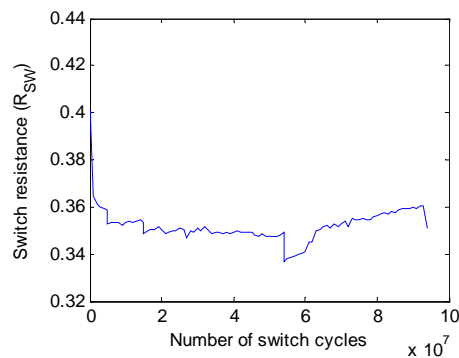
## Measurements and results

- ▶ 1<sup>st</sup> ohmic RF MEMS switch
  - On first phase the resistance increased rapidly
  - On second phase the resistance was measured continuously 100 times after every 10 000 cycles
    - E.g. resistance decreased from 14.8 to 2.1  $\Omega$
    - Measurement environment was ruled out to be the reason



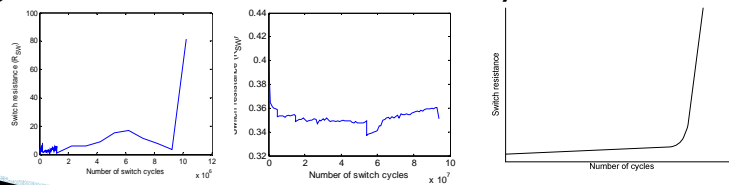
## Measurements and results

- ▶ 2<sup>nd</sup> ohmic RF MEMS switch
  - Switch was cycled successfully nearly 100 million cycles
  - Measured after 1 million cycles
  - No signs before breaking
  - $R_{SW}$  stable
    - Cycles 1 mil – 94 mil variation  $\sim 4\%$



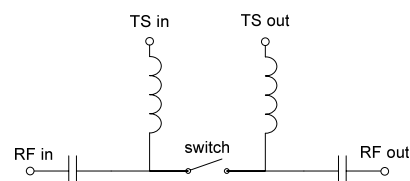
## Measurements and results

- ▶ The measurements prove the effectiveness of the test method
- ▶ Previous studies have shown that switch resistance increases as function of switching number
- ▶ The on-line test method would be effective e.g. in systems with redundancy



## Future directions

- ▶ The next phase is to redo measurements with new components
- ▶ Implement a test setup where live RF-signal is available
- ▶ Comparative measurements with RF and DC
- ▶ Problem: Is there any commercial components?



## Conclusions

- ▶ 1149.4 is useful and one possible method for solving mixed-signal tests on SiP level
- ▶ 1149.4 architecture can be used for the whole life-time of the product
  - from production testing to on-line field testing and system monitoring
- ▶ The presented on-line test method estimates the condition of the ohmic RF MEMS switch through the on-resistance

# Thank you!

**Any questions?**

Jari Hannu  
jari.hannu@ee.oulu.fi